



**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

Complete if Known

Application Number	10/517,483
Filing Date	12-10-2004
First Named Inventor	KAULE
Group Art Unit	2872
Examiner Name	Lavarias
Confirmation No.	6823

Sheet

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Attorney Docket Number

2732-150

NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published	T ²
/ACL/	1	RAI-CHOUDHURY XP- 002251881, SPIE Handbook for Microlithography, <i>Micromachining</i> and Microfabrication, Volume 1: Microlithography (pages 1-16, 2-fold)	

Examiner Signature	/Arnel C. Lavarias/	Date Considered	10/16/2008
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

¹Unique citation designation number. ²Applicant is to place a check mark here if English language Translation is attached.